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11-13-78
AB

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of: Wilk <i>et al.</i>	Docket: TI-24742	
Provisional Serial No.: 60/063,010	Examiner: TBD	
Serial No.: TBD	Art Unit: TBD	
Provisional Filed: 10/23/97		
Filed: Herewith		
For: Low Temperature Method for Forming a Thin, Uniform Oxide		

PRELIMINARY AMENDMENT

September 28, 1998

Ass't Commissioner for Patents
Washington, DC 20231

MAILING CERTIFICATE UNDER 37 CFR § 1.8
I hereby certify that this correspondence is being deposited with the
United States Postal Service as first class mail in an envelope
addressed to: Assistant Commissioner for Patents, Washington,
DC 20231 on

October 26, 1998.

Sue Short

Sue Short

Examiner:

Prior to examination and calculation of fees, please amend the above-identified application
as follows:

IN THE SPECIFICATION:

On Page 1, lines 5-9, delete the table in its entirety and replace with the following:

Filing Date	Appl. No.	Title
7/31/97	08/904,009	Method For Thin Film Deposition On Single-Crystal Semiconductor Substrates
10/23/97	60/063,010	Low Temperature Method for Forming a Thin, Uniform Oxide

On Page 1, lines 14-19, delete the table in its entirety and replace with the following:

Filing Date	Appl. No.	Title
7/31/97	08/904,009	Method For Thin Film Deposition On Single-Crystal Semiconductor Substrates